

Our Docket No: 42P10058D



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Han-Ming Wu et al.

Examiner: Nguyen, Hung

Serial No: 10/759,641

Art Unit: 2851

Filed: January 16, 2004

For: Purging Gas from a
Photolithography Enclosure
Between a Mask Protective
Device and a Pattern Mask

RESPONSE TO OFFICE ACTION

Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

07/14/2005 MBERHE 00000081 10759641

01 FC:1201
02 FC:1251

200.00 OP
120.00 OP

Sir:

In response to the Office Action mailed March 9, 2005, the Applicants respectfully request that the Examiner enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

July 11, 2005

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

Signature

Date